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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In te the Application of: OZAKI, Takashi, et al.

Group Art Unit: 2813

Serial No.: 10/517,765

Examiner: MCCA. L SHEPARD, Sony

Filed: February 3, 2006

P.T.O. Confirmation No.: 6791

SUBSTRATE TREATING APPARATUS AND METHOD FOR For. MANUFACTURING SEMICONDUCTOR DEVICE

## **PETITION FOR EXTENSION OF TIME**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

November 18, 2009

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated July 24, 2009 for one month, from October 24, 2009 to November 24, 2009.

The Commissioner is authorized to charge our Deposit Account in he amount of \$130.00 to cover the cost of the extension for a large entity. In the event that any ad litional fees are due in connection with this paper, please charge our Deposit Account No. 01-2340.

Respectfully submitted,

KRATZ, QUINTOS & HANSON, LLP

Attorney for Applicant Reg. No. 22,631

WGK/ak

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